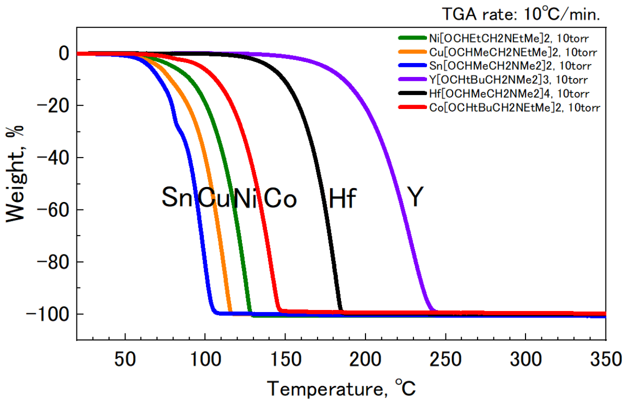

Fig.1: TGA spectra of various kinds of metal aminoalkoxide precursors (under 10 torr).

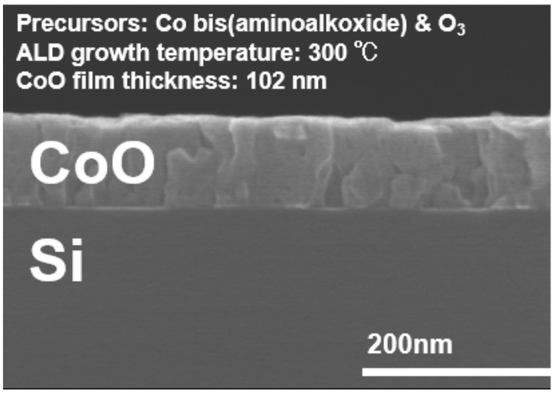

Fig.2: SEM image of ALD CoO film on Si substrate using Co bis(aminoalkoxide) & O_3 co-reactant.

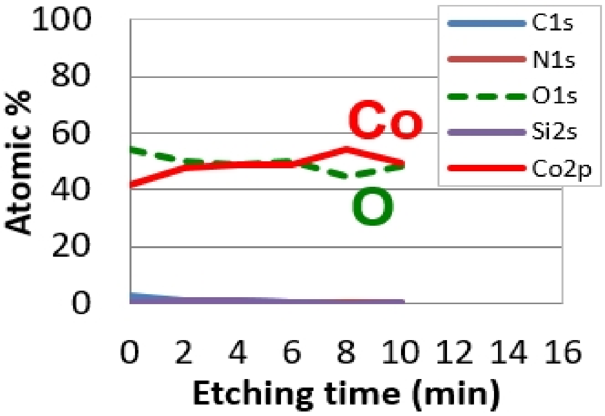

Fig.3: XPS depth profile of pure ALD CoO film on Si substrate using Co bis(aminoalkoxide) & O_3 co-reactant.